
Waveguide Loss

Class: Integrated Photonic Devices
Time: Fri. 8:00am ~ 11:00am.
Classroom: 資電206
Lecturer: Prof. 李明昌(Ming-Chang Lee)

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Optical Loss in Waveguides

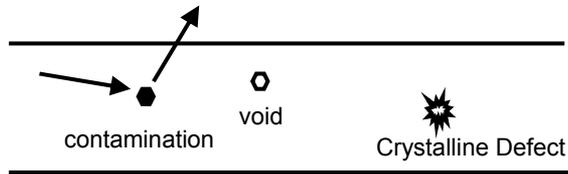
Three major losses in waveguide

- **Scattering Loss**
 - Due to surface roughness
- **Absorption Loss**
 - Due to photons annihilated in materials
- **Radiation Loss**
 - Due to waveguide bending

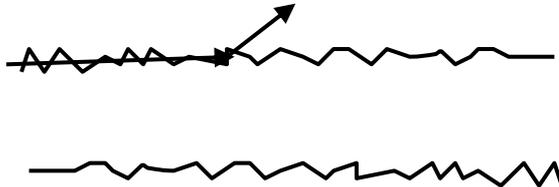
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Scattering Loss

- Volume Scattering



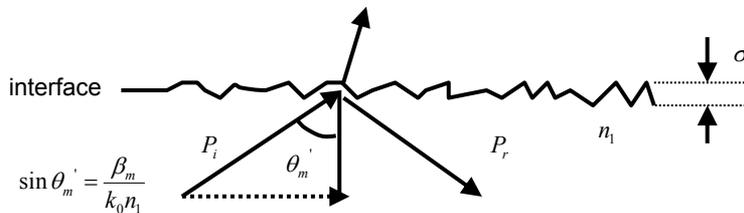
- Surface Scattering (Dominant)



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Surface Scattering Loss (Tien's Model)

- Each reflection induce scattering light



$$\text{Rayleigh Criterion } P_r = P_i \exp\left[-\left(\frac{4\pi\sigma}{\lambda} \cos \theta_m'\right)^2\right]$$

σ : variance of surface roughness

m: mode number

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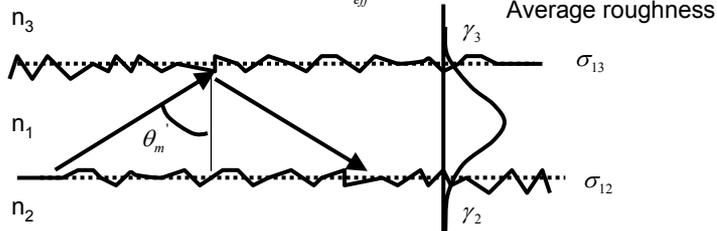
Surface Scattering Loss

To quantitatively describe the optical loss, the exponential attenuation coefficient is generally used. In this case, the intensity (power per unit length) decays along the waveguide.

$$I(z) = I_0 \exp(-\alpha z) \quad I_0 \text{ is the initial intensity at } z = 0$$

$$\alpha_s = A^2 \left(\frac{1}{2} \frac{\cos^3 \theta_m'}{\sin \theta_m'} \right) \underbrace{\left(\frac{1}{t_g + (1/\gamma_2)} + (1/\gamma_3) \right)}_{1/t_{eff}}$$

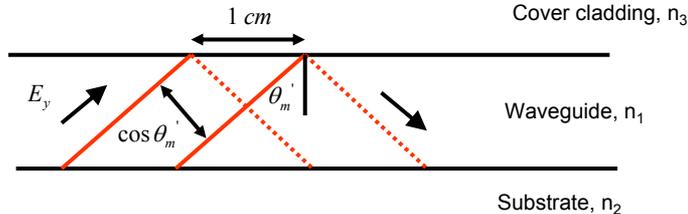
$$A = \frac{4\pi}{\lambda} (\sigma_{13}^2 + \sigma_{12}^2)^{1/2}$$



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Scattering Loss Analysis by Tien's Model

Consider a planar waveguide with TE polarization



The power carried by the incident beam hit on the unit length (1 cm)

$$\frac{c}{8\pi} n_1 E_y^2 \cos \theta_m' \quad E_y \text{ is the field amplitude}$$

According to the Rayleigh criterion, the reflected beam from the upper film surface

$$\frac{c}{8\pi} n_1 E_y^2 \cos \theta_m' \cdot \underbrace{\exp \left[- \left(\frac{4\pi\sigma}{\lambda} \cos \theta_m' \right)^2 \right]}_{\text{Rayleigh criterion}} \quad \sigma : \text{variation of surface roughness}$$

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Scattering Loss Analysis by Tien's Model

Consider the two film surface

$$\frac{4\pi}{\lambda}\sigma \longrightarrow \frac{4\pi}{\lambda}(\sigma_{13} + \sigma_{12})^{1/2}$$

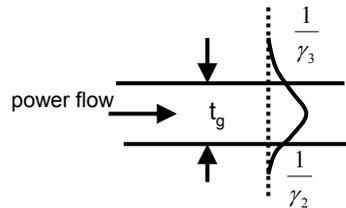
The power lost by surface scattering per unit length is

$$\frac{c}{8\pi} n_1 E_y^2 \cos \theta_m' \cdot \left\{ 1 - \exp \left[- \left(A \cos \theta_m' \right)^2 \right] \right\}$$

$$\approx \frac{c}{8\pi} n_1 E_y^2 A^2 \cos^3 \theta_m'$$

The planar waveguide mode power flow

$$\frac{c}{4\pi} n_1 E_y^2 \sin \theta_m' \cdot \left(t_g + \frac{1}{\gamma_2} + \frac{1}{\gamma_3} \right)$$



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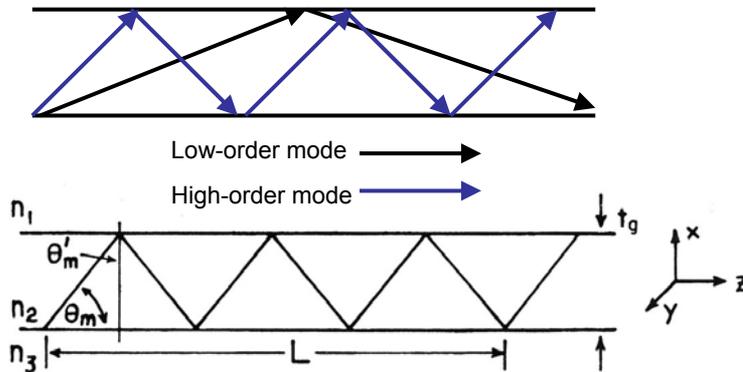
Scattering

The power attenuation per unit length

$$\alpha = A^2 \frac{1}{2} \frac{\cos^3 \theta_m'}{\sin \theta_m'} \left\{ \frac{1}{t_g + (1/\gamma_2) + (1/\gamma_3)} \right\}$$

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Surface Scattering Loss

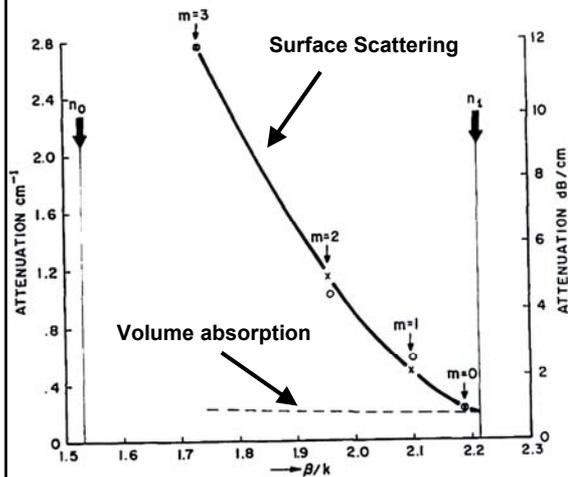


$$N_R = \frac{L}{2t_g \cot \theta_m} \quad \text{Where } m \text{ is mode no.}$$

- High order modes have more reflections from the surface

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Mode Effect



The loss for the $m=3$ waveguide mode is as much as 14 times that of the $m=0$ waveguide mode.

Ta_2O_5

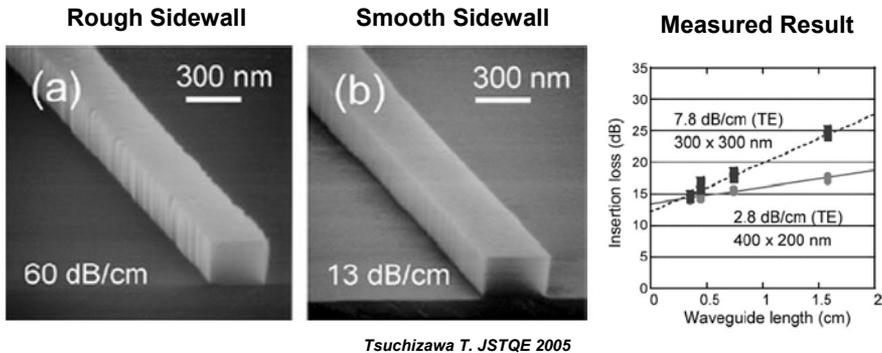
$\lambda = 632.8 \text{ nm}$

$$\alpha : (\text{dB/cm}) = 4.3 \text{ cm}^{-1}$$

Tien, 1971

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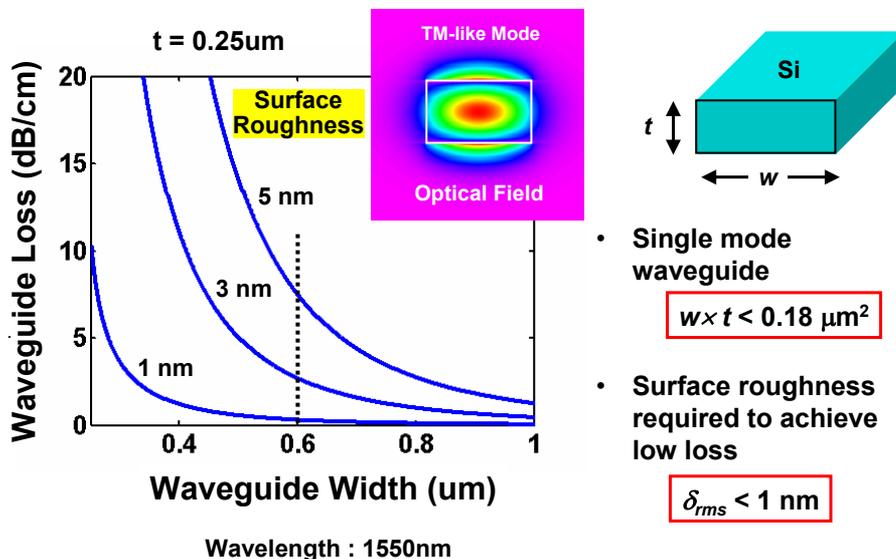
Sidewall Scattering Loss



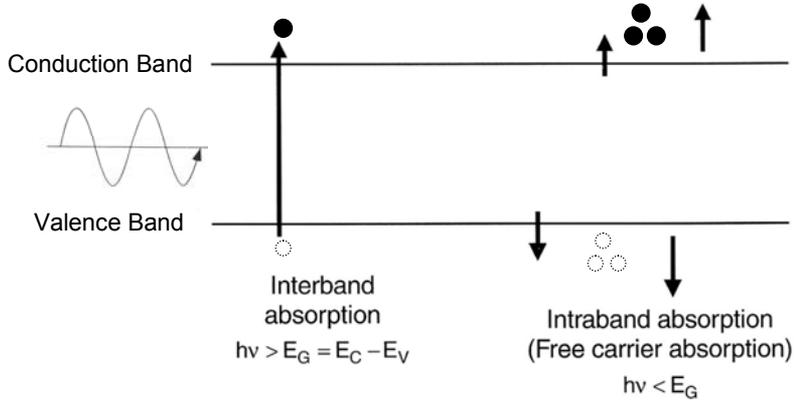
- Sidewall roughness is created during etching process
- The propagation loss is highly related to the roughness for a small-dimension waveguide

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Optical Loss due to Surface Roughness



Absorption Loss

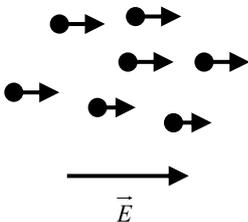


- **Interband absorption** → electron and hole pairs (photodetector) $h\nu > E_g$
- **Intraband absorption** → free carrier scattering (metal) $h\nu < E_g$

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Free Carrier Absorption (Drude Model)

electrons



$$m \frac{d^2x}{dt^2} + mg \frac{dx}{dt} = qE_0 \exp(j\omega t) = -eE_0 \exp(j\omega t)$$

Not harmonic oscillator!

g : damping coefficient due to scattering

m : mass of carrier

$$x = \frac{(eE_0)/m}{\omega^2 - j\omega g} \exp(j\omega t)$$

Recall $\mathbf{D} = \epsilon_0 \mathbf{E} + \mathbf{P}_0 + \mathbf{P}_1 = \epsilon_0 (1 + \chi_0 + \chi_1) \mathbf{E}$

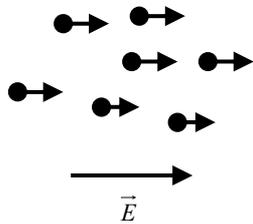
Dielectric polarization
(Dipole Moment)

Free Carrier Effect
(electron or hole)

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Free Carrier Absorption

electrons



$$\mathbf{P}_1 = -Nex = \frac{-(Ne^2)/m}{\omega^2 - j\omega g} E_0 \exp(j\omega t)$$

$$\chi_1 = \frac{-(Ne^2)/(m\epsilon_0)}{\omega^2 - j\omega g} = \chi_1' + j\chi_1''$$

$$\begin{cases} \chi_1' = -\frac{(Ne^2)/(m\epsilon_0)}{\omega^2 + g^2} \\ \chi_1'' = \frac{(Ne^2 g)/(m\omega\epsilon_0)}{\omega^2 + g^2} \end{cases}$$

$$\mathbf{D} = \epsilon_0 \mathbf{E} + \mathbf{P}_0 + \mathbf{P}_1 = \epsilon_0 [(1 + \chi_0 + \chi_1') + j\chi_1''] \mathbf{E} = \epsilon_0 (n_0 + n_1' + jn_1'')^2 \mathbf{E}$$

$$n_1'' = \frac{\chi_1''}{2(n_0 + n_1')}$$

$$\text{where } \chi_1'' \ll 1 + \chi_0 + \chi_1'$$

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What is g?

At steady state, electron move as a constant speed.

That is, $d^2x/dt^2 = 0$

$$mg \frac{dx}{dt} = eE \quad (1)$$

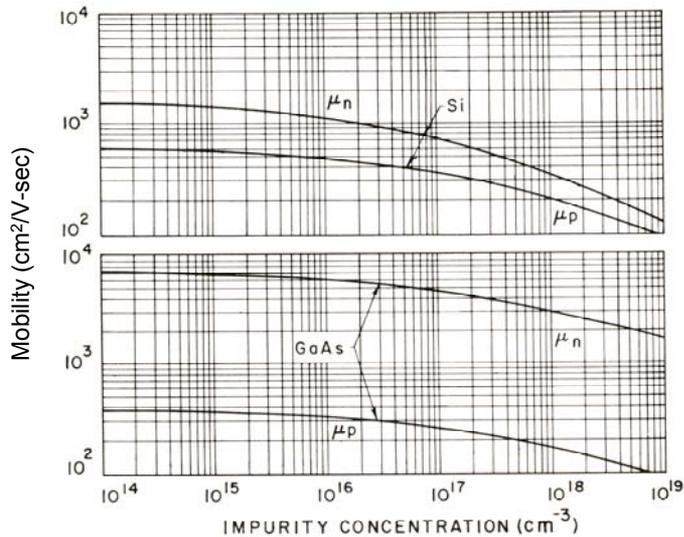
The definition of mobility μ

$$\frac{dx}{dt} = \mu E \quad (2)$$

$$g = \frac{e}{m\mu}$$

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Mobility of Semiconductor



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Free Carrier Absorption

$$I \propto |E|^2 = |E_0|^2 \exp[jk_0(n' + jn'')z] \cdot \exp[-jk_0(n' - jn'')z]$$

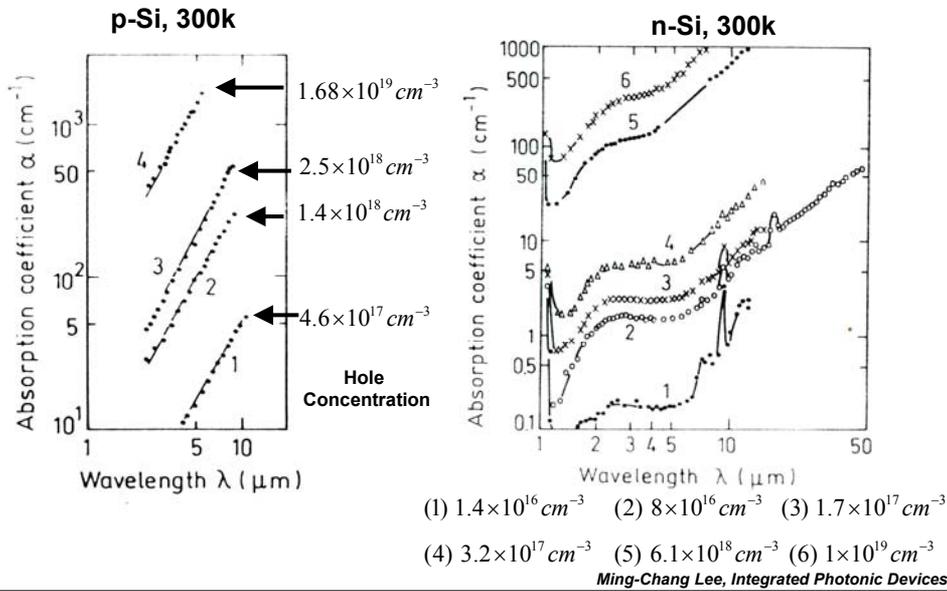
$$= |E_0|^2 \exp[-2k_0 n'' z] = |E_0|^2 \exp[-\alpha z]$$

$$\alpha_{fc} = 2k_0 n'' \approx k_0 \frac{\chi''}{n} = \frac{Ne^3}{m^2 n \epsilon_0 \omega^2 \mu c} \quad (\omega \gg g) \text{ For optical wavelength}$$

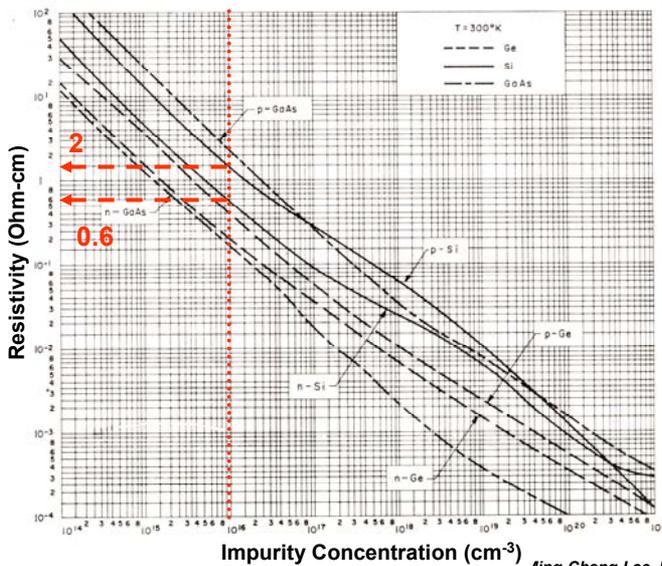
- Free carrier absorption is proportional to the carrier density
- The refractive index is also affected by the free carriers

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Free Carrier Absorption



Resistivity vs. Impurity Concentration



Sze and Irvin

Temperature-Dependent Free Carrier Absorption

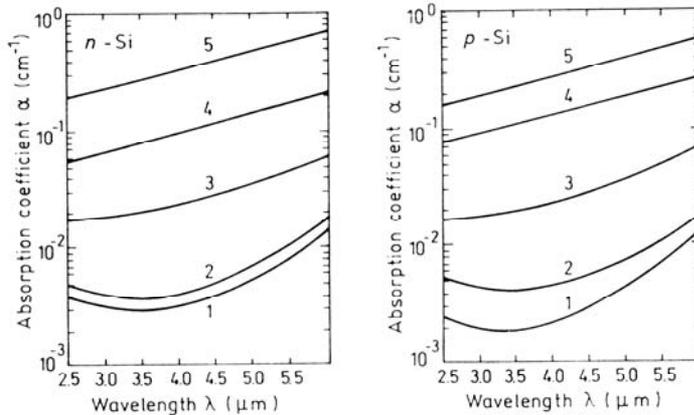
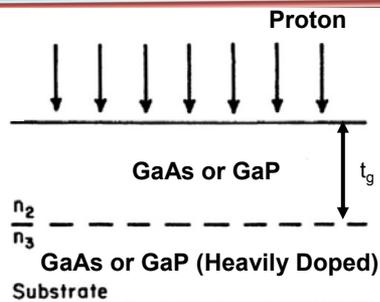
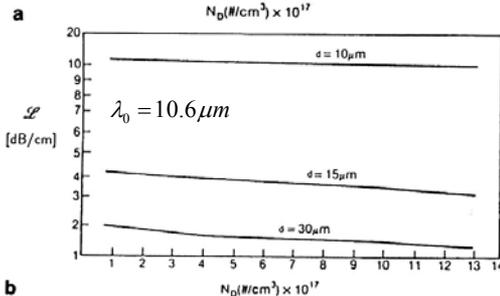
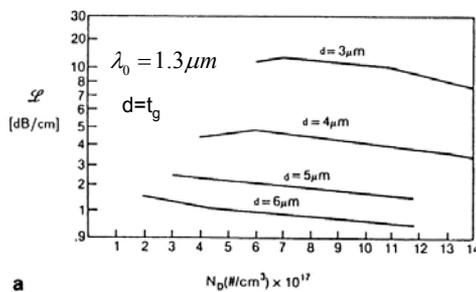


Fig. 1.4.8. Free carrier absorption versus wavelength for high purity Si at different temperatures (Runyan [1966]). Temperatures are 1. 300 K, 2. 473 K, 3. 573 K, 4. 623 K, 5. 673 K (Figure reprinted with permission of McGraw-Hill Book Co.).

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Free Carrier Absorption on Proton Bombardment Waveguide

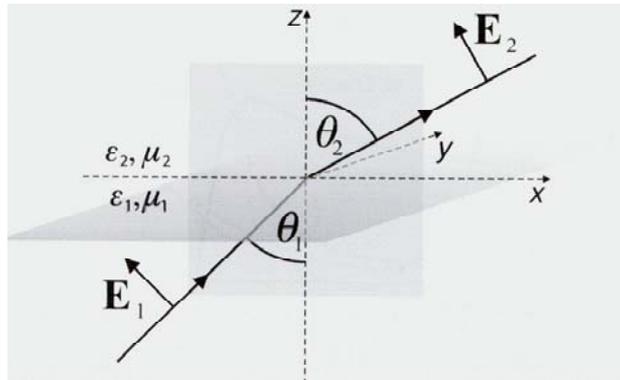


$$(N_2 - N_1) \geq \frac{\epsilon_0 m^* \pi^2 c^2}{4t_g^2 e^2}$$

The major loss comes from the evanescent wave penetrating in substrate

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Surface Plasmons

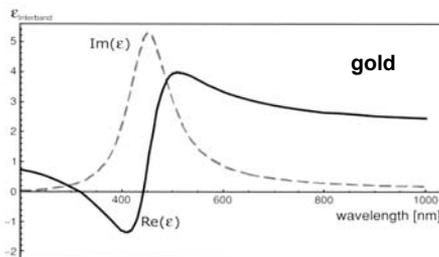


- The interaction of metals with electromagnetic radiation is largely dictated by the free electrons in the metal.
- Most metals possess a negative dielectric constant at optical frequency
- Only the surface can support optical wave propagation (why?)

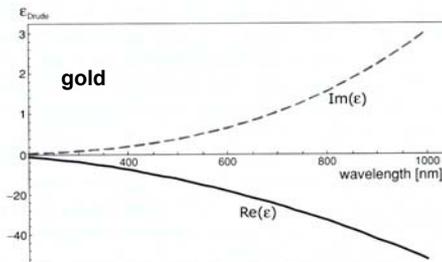
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Optical Properties of Noble Metals

Dipole Dispersion



Free-Carrier Dispersion

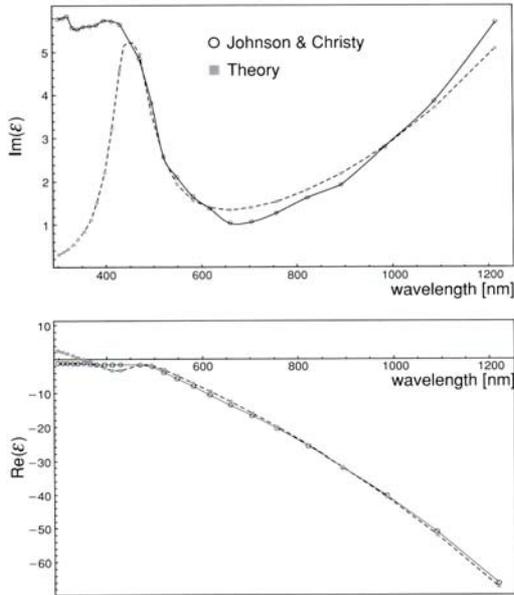


$$\left\{ \begin{array}{l} \chi'_{dipole}(\omega) = \frac{(Ne^2/m)(\omega_0^2 - \omega^2)}{\varepsilon_0[(\omega_0^2 - \omega^2)^2 + \zeta^2\omega^2]} \\ \chi''_{dipole}(\omega) = \frac{(Ne^2/m)(\zeta\omega)}{\varepsilon_0[(\omega_0^2 - \omega^2)^2 + \zeta^2\omega^2]} \end{array} \right.$$

$$\left\{ \begin{array}{l} \chi'_{free-carrier}(\omega) = -\frac{(Ne^2)/(m\varepsilon_0)}{\omega^2 + g^2} \\ \chi''_{free-carrier}(\omega) = \frac{(Ne^2g)/(m\omega\varepsilon_0)}{\omega^2 + g^2} \end{array} \right.$$

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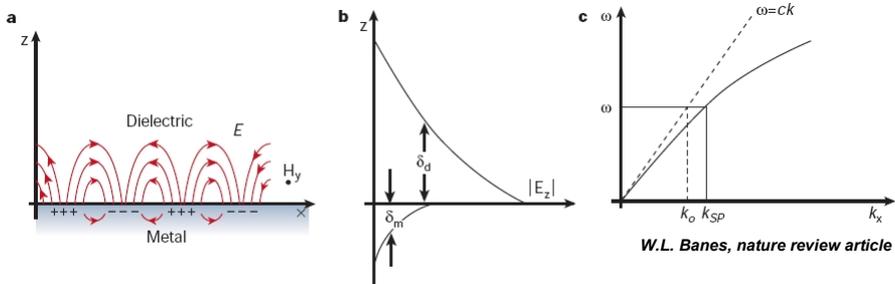
Measure dielectric function of gold



Combine dipole dispersion and free-carrier dispersion

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Surface Plasmons at plane interface

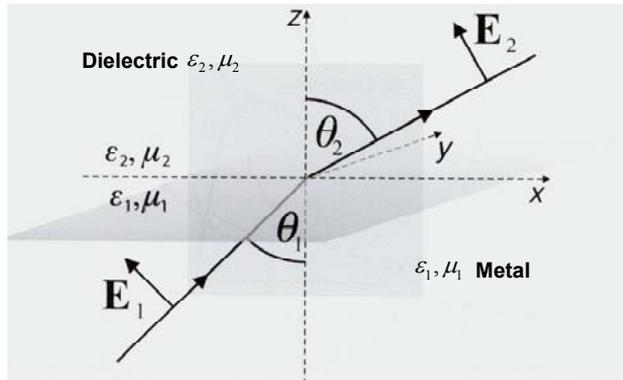


W.L. Banes, *nature review article*

- EM wave and surface charge are oscillating.
- The fields in the perpendicular direction decay exponentially.
- The momentum of SP is larger than the free space photon.

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Surface Plasmons at plane interface



Mathematically, the solution has to satisfy the wave equation

$$\nabla \times \nabla \times \mathbf{E}(r, \omega) - \frac{\omega^2}{c^2} \varepsilon(r, \omega) \mathbf{E}(r, \omega) = 0$$

where $\varepsilon(r, \omega) = \varepsilon_1(\omega)$ $z < 0$ $\varepsilon(r, \omega) = \varepsilon_2(\omega)$ $z > 0$

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Surface Plasmons at plane interface

TE wave or s-wave can not be a solution of surface plasmonic wave (H can not satisfy the boundary condition)

Consider a TM wave or p-wave,

$$E_i = \begin{pmatrix} E_{i,x} \\ 0 \\ E_{i,z} \end{pmatrix} \exp(jk_x x - j\omega t) \exp(jk_z z) \quad \text{where } i=1,2$$

Since the x-direction wave vector is conserved or Snell's law

$$k_x^2 + k_{i,z}^2 = \varepsilon_i k^2 \quad \text{where } k = \frac{\omega}{c}$$

Since both spaces are source-free; that is, $\nabla \cdot \mathbf{D} = 0$

$$k_x E_{i,x} + k_{i,z} E_{i,z} = 0 \quad (\text{a})$$

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Surface Plasmons at plane interface

Consider the boundary condition,

$$\begin{aligned} E_{1,x} - E_{2,x} &= 0 \\ \varepsilon_1 E_{1,z} - \varepsilon_2 E_{2,z} &= 0 \end{aligned} \quad (b)$$

Combine (a) and (b), since the electric fields are not trivial solutions, the determinant of respective matrix has to be zero; then

$$\varepsilon_1 k_{2,z} - \varepsilon_2 k_{1,z} = 0$$

Therefore,

$$k_x^2 = \frac{\varepsilon_1 \varepsilon_2}{\varepsilon_1 + \varepsilon_2} k^2 = \frac{\varepsilon_1 \varepsilon_2}{\varepsilon_1 + \varepsilon_2} \frac{\omega^2}{c^2} \quad \text{and} \quad k_{i,z} = \frac{\varepsilon_i^2}{\varepsilon_1 + \varepsilon_2} k^2 \quad i = 1, 2$$

recall $k_x^2 + k_{i,z}^2 = \varepsilon_i k^2$

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Surface Plasmons at plane interface

Since the surface plasmonic mode are evanescent on the two sides of interface

k_x should be real and $k_{i,z}$ should be imaginary

Therefore

$$\begin{aligned} \varepsilon_1(\omega) \cdot \varepsilon_2(\omega) &< 0 \\ \varepsilon_1(\omega) + \varepsilon_2(\omega) &< 0 \end{aligned}$$

The dielectric functions must be negative with an absolute value exceeding that of the other.

Nobel metals such as gold and silver, have a large negative real part of the dielectric constant along with small imaginary part

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Properties of surface plasmonic waves

Consider the metal dielectric

$$\epsilon_1 = \epsilon_1' + j\epsilon_1''$$

Suppose the imaginary part is much smaller than the real part and ϵ_2 is positive real, the wave number of SP mode

$$k_x = k_x' + jk_x''$$

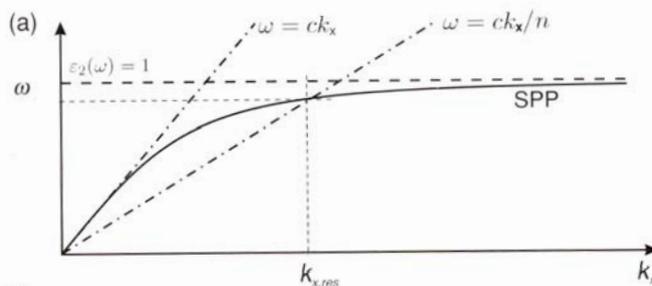
where

$$\begin{cases} k_x' \approx \sqrt{\frac{\epsilon_1' \epsilon_2}{\epsilon_1' + \epsilon_2}} \frac{\omega}{c} \\ k_x'' \approx \sqrt{\frac{\epsilon_1' \epsilon_2}{\epsilon_1' + \epsilon_2}} \frac{\epsilon_1'' \epsilon_2}{2\epsilon_1'(\epsilon_1' + \epsilon_2)} \frac{\omega}{c} \end{cases}$$

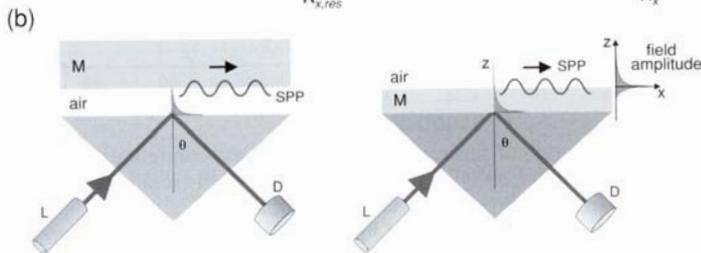
and $k_{1,z} = \frac{\omega}{c} \sqrt{\frac{\epsilon_1'^2}{\epsilon_1' + \epsilon_2}} \left[1 + j \frac{\epsilon_1''}{2\epsilon_1'} \right]$ $k_{2,z} = \frac{\omega}{c} \sqrt{\frac{\epsilon_2^2}{\epsilon_1' + \epsilon_2}} \left[1 - j \frac{\epsilon_1''}{2(\epsilon_1' + \epsilon_2)} \right]$

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Excitation of Surface Plasmonic Wave

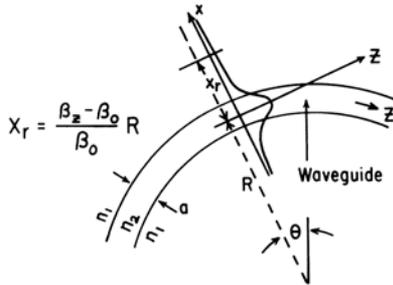


In this case, SPP can not be directly coupled from air



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Radiation Loss

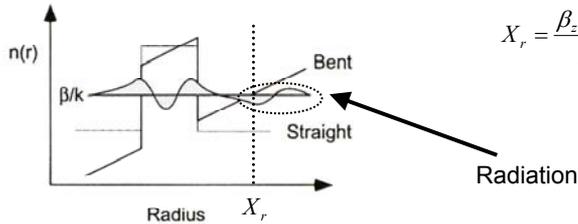


$$X_r = \frac{\beta_z - \beta_0}{\beta_0} R$$

$$(R + X_r) \frac{d\theta}{dt} = \frac{\omega}{\beta_0}$$

$$R \frac{d\theta}{dt} = \frac{\omega}{\beta_z}$$

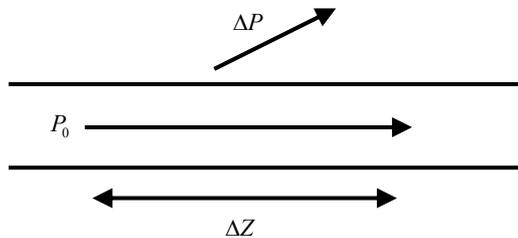
The angular phase velocity should be the same.



$$X_r = \frac{\beta_z - \beta_0}{\beta_0} R$$

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What is Attenuation Coefficient (α)?



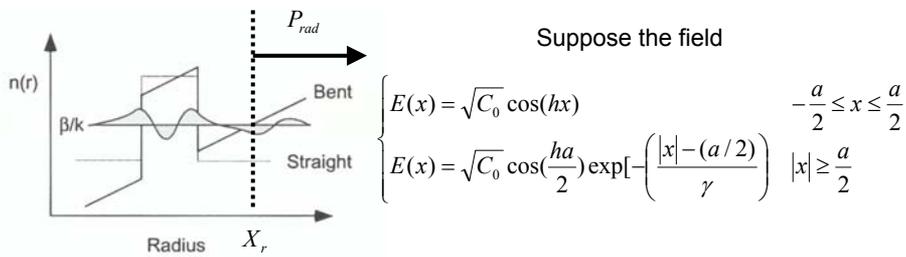
$$\alpha = -\frac{1}{P(z)} \frac{dP(z)}{dz} \quad (\text{Because } P(z) = P_0 \exp(-\alpha z))$$

$$\approx -\frac{1}{P(z_0)} \frac{\Delta P(z)}{\Delta z}$$

← Dissipated Power
← Propagation length

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What is α due to Radiation Loss?



Total Power $\rightarrow P(z_0)$

$$P_{total} = \int_{-\infty}^{\infty} E^2(x) dx = C_0 \left[\frac{a}{2} + \frac{1}{2h} \sin(ha) + \gamma \cos^2\left(\frac{ha}{2}\right) \right]$$

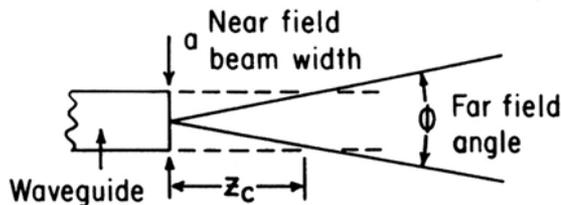
Radiated Power $\rightarrow \Delta P(z)$

$$P_{rad} = \int_{X_r}^{\infty} E^2(x) dx = C_0 \frac{\gamma}{2} \cos^2\left(\frac{ha}{2}\right) \exp\left(-\frac{2}{\gamma} \left(X_r - \frac{a}{2}\right)\right)$$

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What is Attenuation Coefficient (α)?

The propagation length of unguided mode (analogy to a truncated waveguide)



$$Z_c = \frac{a}{\phi} = \frac{a^2}{2\lambda} \quad (\text{Because } \sin\left(\frac{\phi}{2}\right) = \frac{\lambda}{a}) \quad \begin{array}{l} a: \text{ waveguide width} \\ \lambda: \text{ wavelength} \end{array}$$

The attenuated coefficient:

$$\alpha = \frac{\frac{\gamma}{2} \cos^2\left(\frac{ha}{2}\right) \exp\left(-\frac{2}{\gamma} \frac{\beta_z - \beta_0}{\beta_0} R\right) 2\lambda_1 \exp\left(\frac{a}{\gamma}\right)}{\left[\frac{a}{2} + \frac{1}{2h} \sin(ha) + \gamma \cos^2\left(\frac{ha}{2}\right)\right] a^2}$$

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What is α due to Radiation Loss?

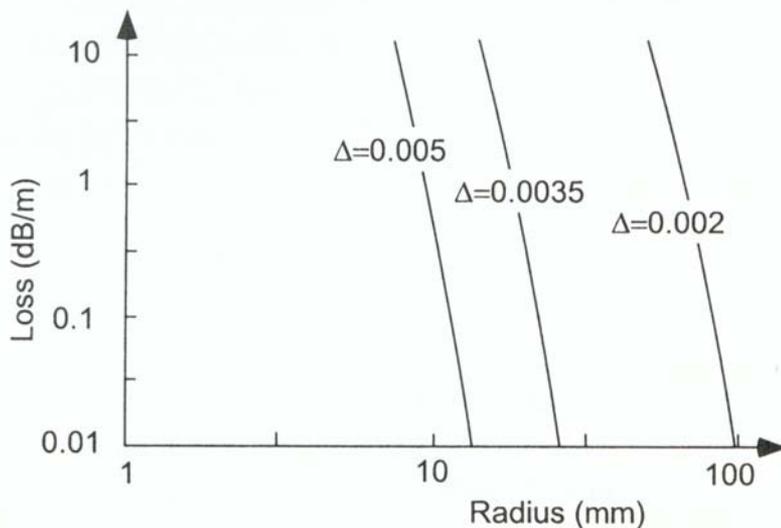
$$\alpha = \frac{\frac{\gamma}{2} \cos^2\left(\frac{ha}{2}\right) \exp\left(-\frac{2}{\gamma} \frac{\beta_z - \beta_0}{\beta_0} R\right) 2\lambda_1 \exp\left(\frac{a}{\gamma}\right)}{\left[\frac{a}{2} + \frac{1}{2h} \sin(ha) + \gamma \cos^2\left(\frac{ha}{2}\right)\right] a^2} = C_1 \exp(-C_2 R)$$

$$C_2 = \frac{2}{\gamma} \frac{\beta_z - \beta_0}{\beta_0}$$

- The attenuation coefficient decreases with the bending radius
- The attenuation coefficient decrease with the index contrast

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What is Attenuation Coefficient (α)?



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Other Losses --- Intersection

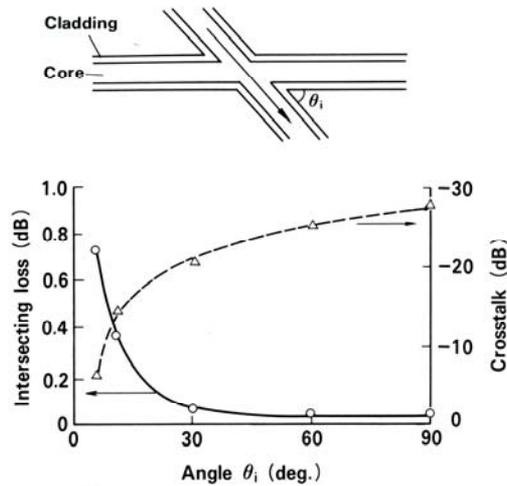


FIG. 10.13 Crosstalk (or intersection) loss versus cross angle in the silica single-mode crosstalk waveguide.³² A. Himeno, M. Kobayashi, and H. Terui, *Electron. Lett.* 1985, IEE.

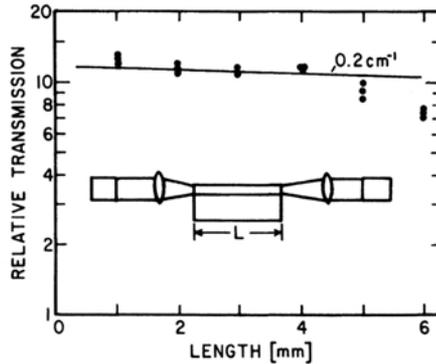
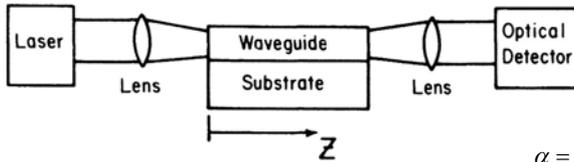
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Waveguide Loss Measurement

- **How to distinguish the loss?**
 1. Waveguide loss or coupling loss?
 2. Waveguide loss of fundamental mode or high-order modes?
 3. Scattering loss, absorption loss, or radiation loss?

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End-Fire Coupling Loss Measurement

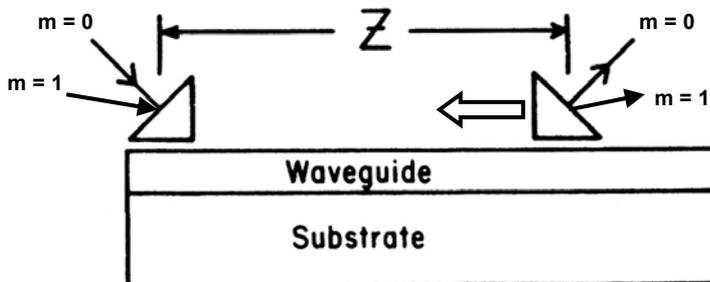


$$\alpha = \frac{\ln(P_1/P_2)}{Z_2 - Z_1} \quad \text{for } Z_2 > Z_1$$

- **Advantage**
 - Simple and direct
- **Disadvantage**
 - Alignment sensitive
 - End face condition should be consistent
 - Can't distinguish the loss associated with different mode number

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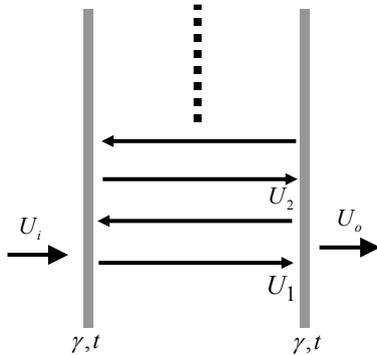
Prism-Coupled Loss Measurement



- **Advantage**
 - Can measure the loss from different modes
 - Alignment insensitive
 - End face quality is not required
- **Disadvantage**
 - Less accurate (It is difficult to reproduce the coupling loss)

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Fabry-Perot



γ : reflection
 t : transmission
 $t^2 = 1 - \gamma^2$

$$U_1 = U_i \cdot t \exp(-j\varphi) \exp\left(-\frac{\alpha}{2}L\right)$$

$$U_2 = U_1 \cdot \gamma^2 \exp(-j2\varphi) \exp(-\alpha L)$$

$$U_0 = \sum_n U_n$$

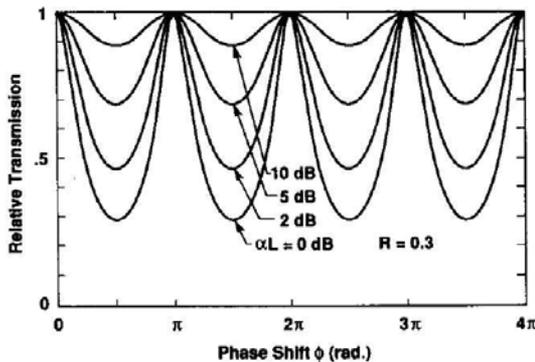
$$I_0 = U_0 \cdot U_0^* = \frac{(1 - \gamma^2)^2 \exp(-\alpha L)}{(1 - R)^2 + 4R \sin^2 \varphi}$$

where $R = \gamma^2 \exp(-\alpha L)$

$$\alpha = -\frac{1}{L} \ln \left(\frac{1}{\gamma^2} \frac{\sqrt{I_{\max}/I_{\min}} - 1}{\sqrt{I_{\max}/I_{\min}} + 1} \right) \quad \begin{matrix} I_{\max} : \varphi = n\pi \\ I_{\min} : \varphi = \frac{1}{2}(2n+1)\pi \end{matrix}$$

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Fabry-Perot Loss Measurement



- **Advantage**
 - Alignment insensitive
- **Disadvantage**
 - End face condition should be consistent
 - Only for single mode waveguide
 - Light source should be single frequency

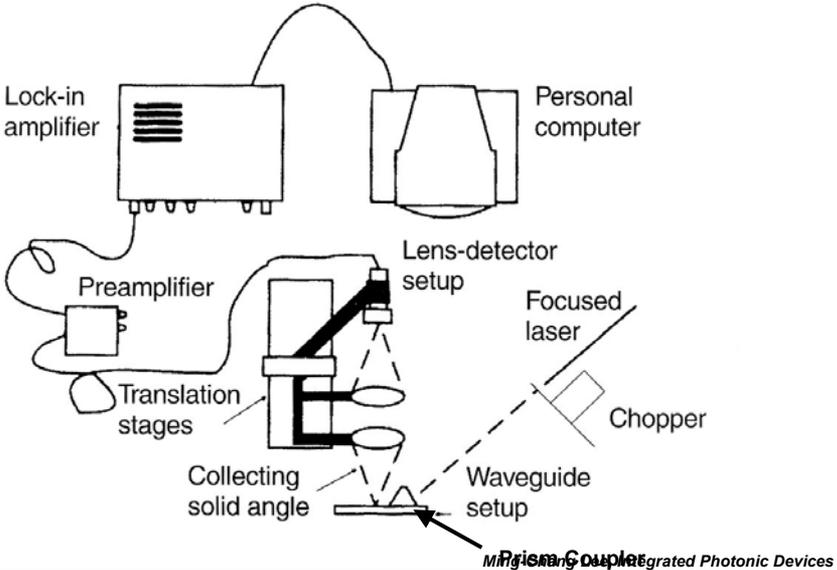


γ^2 : Reflectivity

$$\alpha = -\frac{1}{L} \ln \left(\frac{1}{\gamma^2} \frac{\sqrt{I_{\max}/I_{\min}} - 1}{\sqrt{I_{\max}/I_{\min}} + 1} \right)$$

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Scattering Loss Measurement



Scattering loss Measurement by Image Analysis

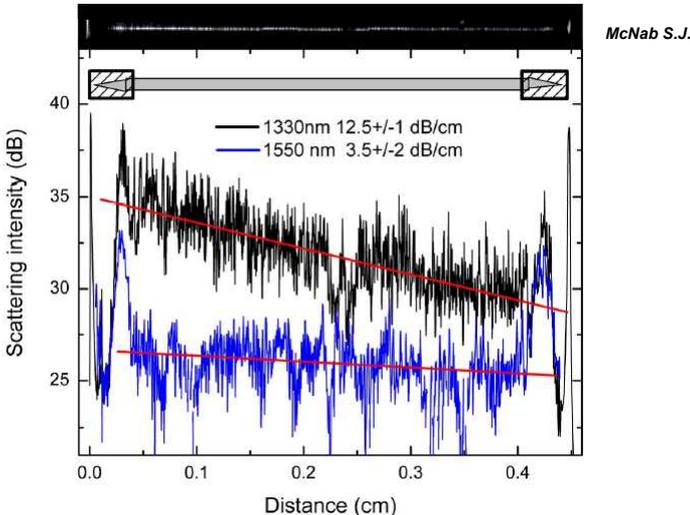


Fig. 3. Intensity of light scattered vertically from the reference optical circuit of Fig. 1(b) with a 450nm wide strip waveguide for TE polarized light. Blue curve corresponds to the wavelength of 1550nm and black to 1330nm. Inset: Image of the vertically scattered light acquired by the IR camera. Several of such images were averaged to produce the traces in the main figure.